**DOCKET NO: 245742US26** 

## IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF :

HIROMI SAKIMA : EXAMINER: CARRILLO, B.

SERIAL NO: 10/715,859 :

FILED: NOVEMBER 19, 2003 : GROUP ART UNIT: 1792

FOR: PLASMA PROCESSING METHOD :

AND APPARATUS

## STATEMENT OF SUBSTANCE OF INTERVIEW UNDER MPEP § 713.04

COMMISSIONER FOR PATENTS ALEXANDRIA, VIRGINIA 22313

SIR:

As a result of the interview conducted on September 3, 2008, please amend the above-identified application as follows:

Remarks/Arguments begin on page 2 of this paper.

## REMARKS/ARGUMENTS

On September 2, 2008, the Examiner assigned to this application requested authorization for an examiner's amendment to place the application in condition for allowance.

The examiner's amendment would amend independent Claims 1 and 6 to specify that the supplying the second CF-based gas includes supplying CF<sub>4</sub>, O<sub>2</sub>, and Ar. Claims 21 and 25 would be amended to remove redundancies in view of the amendment to independent Claims 1 and 6. The examiner's amendment would also amend the fifth paragraph of Claim 6 as follows:

wherein the dry cleaning step is performed by supplying into the chamber a deposit removing gas for removing the deposits and a dummy substrate etching gas eapable of etching that etches the dummy substrate to stabilize and stabilizes an etching rate of the second plasma etching step, which is carried out right after the dry cleaning step,

Additionally, the examiner's amendment would amend Claim 24 as follows:

Claim 24 (New): The plasma processing method of Claim 1, wherein the first and the second plasma processing steps and the dry cleaning step are carried out without a seasoning step occurring between the dry cleaning and the second plasma processing step, the second plasma processing step is stabilized by the cleaning step such that an etch rate at a beginning of the second plasma processing step is approximately equal to an etch rate five minutes after beginning the plasma processing step.

The examiner's amendment would make a similar change to Claim 28.

On September 3, 2008, authorization was provided for the above-noted examiner's amendment.

Respectfully submitted,

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